



Laser Micro- and Nano- Processing

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Message from the Guest Editors

Dear Colleagues,

Numerous recent technological advances rely on controllable micro- and nano-fabrication techniques to improve the performance of devices in various applications (e.g., in biomedicine, communications, and energy harvesting). Lasers are uniquely suited for a wide variety of fabrication applications at both the micro- and the nano-scales, in both the production and research environments. In light of this, we announce a Special Issue on "Laser Micro- and Nano Processing" and invite original contributions. We seek not only to report recent developments, but also to mold the future of the field. Example topics include matter interactions, direct write processes, ultra-short pulse laser processing, surface treatment, and 3-D micro- and nano-fabrication.

We look forward to receiving your contributions.

Prof. Dr. Costas Fotakis

Dr. Maria Farsari

Guest Editors





Editor-in-Chief

Message from the Editor-in-Chief

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